



Objective:

To create a Phase Shifting (PS) method for 3D scanning robust to global illumination effects and with low decoding computational cost.

Related work:

- □ Multiple PS [1] projects patterns of multiple frequencies and uses Temporal Phase Unwrapping [2], which is accurate and computationally efficient, but it is not robust to global illumination effects.
- □ Micro PS [3] is robust to global illumination effects, because it uses only high frequency patterns, but decoding requires search in a LUT which is inefficient and produces frequent errors.

Embedded PS:

- High frequency patterns robust to global illumination
- □ Embedded low frequencies permit efficient and accurate phase unwrapping
- Every projected frequency generates a depth measurement, multiple measurements combined produce more accurate results.

Coding Method:

Let be $\{T_1, \dots, T_M\}$ real numbers greater than 1. We define M embedded frequencies F_m as:

$$F_m = \frac{1}{T_1} \cdots \frac{1}{T_m}.$$

We define M pattern frequencies f_m as:

$$\begin{bmatrix} f_1 \\ f_2 \\ f_3 \\ \vdots \\ f_M \end{bmatrix} = \begin{bmatrix} 1 & 0 & 0 & & 0 \\ 1 & 1 & 0 & \dots & 0 \\ 1 & 0 & 1 & & 0 \\ \vdots & \ddots & 0 \\ 1 & 0 & 0 & \dots & 1 \end{bmatrix} \begin{bmatrix} F_1 \\ F_2 \\ F_3 \\ \vdots \\ F_M \end{bmatrix}$$

Create a sinusoidal pattern for each of the M pattern frequencies.

- **Example**: if $T_1=16$, $T_2=8$, and $T_3=8$; then
- embedded frequencies are $F_1=1/16$, $F_2=1/128$, and $F_3=1/1024$
- pattern frequencies are $f_1=1/16$, $f_2=1/14.22$, and $f_3=1/15.75$



Embedded Phase Shifting: Robust Phase Shifting with Embedded Signals Kilho Son Daniel Moreno Gabriel Taubin

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Decoding Method:

Use image intensities to recover the phase vector:

 $\mathbf{u} = [o, c_1, s_1, \dots, c_M, s_M]^T, \ c_m = a_m \cos(\omega_m \phi_m), \ s_m = a_m \sin(\omega_m \phi_m).$

Each relative phase ϕ_m corresponds to a pattern frequency. Extract the embedded frequencies:

 $\Phi_1 \equiv \phi_1$ $\Phi_m = \phi_m - \phi_1 \quad \text{for } m > 1.$

Use Temporal Phase Unwrapping [2] to unwrap the embedded frequency phases Φ_m and pattern frequency phases ϕ_m . Each pattern frequency phase provides a separate depth measurement.



Surface Properties:

a) Lambertian Surface: in the absence of global illumination effects Embedded PS and Multiple PS performs similarly.

b) Specular Concave Surface: Embedded PS and Micro PS performs well in the presence of global illumination effects



Multiple Measurements: 3D models from same image data using only <u>a single measurement (blue)</u> and <u>multiple measurements (red)</u>. The latter one has less noise and it is more accurate.



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Profile of a metal plane:

Micro PS produces frequent unwrapping errors, some of them can be corrected with a median

Multiple PS and Embedded PS show now errors.

